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IEEE JNL IEEE Journal or Magazine

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IEEE STD IEEE Standard

## Select Article Information

- ☐ 1. **Polymer-based electrospray chips for mass spectrometry**  
 Xuan-Qi Wang; Desai, A.; Yu-Chong Tai; Licklider, L.; Lee, T.D.;  
 Micro Electro Mechanical Systems, 1999. MEMS '99. Twelfth IEEE International Conference on  
 17-21 Jan. 1999 Page(s):523 - 528  
 Digital Object Identifier 10.1109/MEMSYS.1999.746883  
[AbstractPlus](#) | Full Text: [PDF](#)(788 KB) IEEE CNF
- ☐ 2. **A MEMS electrospray nozzle for mass spectroscopy**  
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 Solid State Sensors and Actuators, 1997. TRANSDUCERS '97 Chicago., 1997 International  
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 Volume 2, 16-19 June 1997 Page(s):927 - 930 vol.2  
 Digital Object Identifier 10.1109/SENSOR.1997.635254  
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- ☐ 3. **Micromachined membrane particle filters**  
 Yang, X.; Yang, J.M.; Wang, X.Q.; Meng, E.; Tai, Y.C.; Ho, C.M.;  
 Micro Electro Mechanical Systems, 1998. MEMS 98. Proceedings., The Eleventh Annual  
 International Workshop on  
 25-29 Jan. 1998 Page(s):137 - 142  
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